

TECHNICAL DATA SHEET

Levon™ PT40K Plasma Cleaner (40 kHz)

40 kHz · automatic matching · PT40K-BE 0–500 W (maximum 1,000 W) · PT40K-SE 0–1,000 W · 6.4 L chamber



Levon™ PT40K Plasma Cleaner (40 kHz) — Representative Configuration

The Levon™ PT40K Plasma Cleaner (40 kHz) is a plasma cleaner with an automatic matcher and an aluminum alloy chamber, offered in two configurations. Image shown for reference (PT40K-BE); final configuration is confirmed in the quotation.

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Revision Date **10/21/2026**

SECTION I

Product Overview

Levon™ PT40K Plasma Cleaner (40 kHz) is a plasma cleaner with a 40 kHz power supply, automatic matching and a 6.4 L aluminum alloy chamber (226 × 126 × 224 mm) for substrates up to 8 inches (200 mm) in diameter. It is offered as the PT40K-BE (0–500 W, maximum 1,000 W; single float flowmeter) and the PT40K-SE (0–1,000 W; dual float flowmeters).

Both PT40K configurations have a vacuum level of < 10 Pa, a 300 s time setting, a specified vacuum-pump pumping speed of 4 m³/h, a 30 s gas stabilization time and dimensions of 500 × 480 × 290 mm (W × D × H). They differ in power and gas control (see the configuration comparison).

SECTION II

Core Advantages

- **40 kHz with automatic matching** Power supply at 40 kHz with an automatic matcher.
- **Substrates up to 8 inches** For substrates up to 8 inches (200 mm) in diameter.
- **Surface treatment** Plasma treatment for surface modification.
- **Up to 1,000 W** 0–500 W (maximum 1,000 W) on the PT40K-BE; 0–1,000 W on the PT40K-SE.
- **Two gas-control options** Single float flowmeter (PT40K-BE) or dual float flowmeters (PT40K-SE).
- **Time setting** Time setting: 300 s.

SECTION III

Specifications

Technical data — PT40K

Specifications	
Parameter	Specification
Brand	Levon™ by ACS Material
Product Name	Levon™ PT40K Plasma Cleaner (40 kHz)
Models	PT40K-BE / PT40K-SE
SKU #	LVPT40BE (PT40K-BE) / LVPT40SE (PT40K-SE)
Product type	Plasma cleaner
Frequency	40 kHz
Matching	Automatic matching
Chamber size	226 × 126 × 224 mm
Chamber material	Aluminum alloy
Chamber volume	6.4 L
Vacuum level	< 10 Pa
Time setting	300 s
Vacuum pump	Pumping speed 4 m ³ /h
Gas stabilization time	30 s
Applicable substrates	Up to 8 inches (200 mm) in diameter
Dimensions [W × D × H]	500 × 480 × 290 mm
Packing	Carton packaging
Warranty	1-year product warranty

Configurations — PT40K-BE / PT40K-SE

Configurations		
Parameter	PT40K-BE	PT40K-SE
SKU #	LVPT40BE	LVPT40SE
Power	0–500 W (maximum 1,000 W)	0–1,000 W
Gas control	Single float flowmeter	Dual float flowmeters

Scope of delivery

- **Standard configuration:** one PT40K main unit (PT40K-BE or PT40K-SE, as ordered), carton packaging.
- **Configuration** — PT40K-BE = SKU LVPT40BE; PT40K-SE = SKU LVPT40SE. Vacuum pump supply, electrical input requirements and process gas requirements are confirmed in the quotation.

SECTION IV**Applications**

For plasma surface treatment of substrates up to 8 inches (200 mm) in diameter in a 6.4 L chamber. The PT40K is for laboratory plasma surface treatment.

Product value: 40 kHz plasma surface treatment with automatic matching for substrates up to 8 inches, in two power and gas-control configurations (PT40K-BE / PT40K-SE).

Revision Date: 10/21/2026

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